







an Open Access Journal by MDPI

Structured Optical Surfaces and Interfaces, Fabrication and Characterization

Guest Editor:

Prof. Dr. Menelaos K. Poutous

Department of Physics & Optical Science, The University of North Carolina at Charlotte, 9201 University City Boulevard, Charlotte, NC 28223, USA

Deadline for manuscript submissions:

closed (30 September 2021)

Message from the Guest Editor

It is my pleasure to invite your contributions to this Special Issue, seeking to collect research papers and review articles that focus on the following: (1) fabrication and, (2) characterization of optical structured surfaces and interfaces; including evolutionary, disruptive, revolutionary, and incremental techniques and methods.

- micro- and nano-structured optical surfaces
- bio-mimetic optical structures
- layered metamaterials
- surface hierarchical structures
- optical nano-surface fabrication
- plasmonic and photonic nanopillars
- nanorod arrays
- nanosphere optical layers
- lithographic nano/micro-fabrication
- optical surface modification
- subwavelength diffractive optics
- surface holograms
- nano-imprinting lithography
- optical surface characterization
- metamaterial absorbers
- functional optical surfaces













an Open Access Journal by MDPI

Editor-in-Chief

Prof. Dr. Ai-Qun Liu

1. Department of Electrical and Electronic Engineering, The Hong Kong Polytechnic University, Hong Kong, China 2. School of Electrical and Electronic Engineering, Nanyang Technological University, Singapore 639798, Singapore

Message from the Editor-in-Chief

You are invited to contribute research articles or comprehensive reviews for consideration and publication in *Micromachines* (ISSN 2072-666X). *Micromachines* is published in the open access format. Research articles, reviews and other contents are released on the internet immediately after acceptance. The scientific community and the general public have unlimited free access to the content as soon as it is published. As an open access journal, *Micromachines* is supported by the authors or their institutes by payment of article processing charges (APC) for accepted papers. We are pleased to welcome you as our authors.

Author Benefits

Open Access: free for readers, with article processing charges (APC) paid by authors or their institutions.

High Visibility: indexed within Scopus, SCIE (Web of Science), PubMed, PMC, Ei Compendex, dblp, and other databases.

Journal Rank: JCR - Q2 (Instruments and Instrumentation) / CiteScore - Q1 (Mechanical Engineering)

Contact Us